



TECHNOLOGY

Focused Ion Beam Fabrication of Fiber Probes for Use in Near-Field Scanning Optical Microscopy

OVERVIEW

A new focused ion-beam (FIB) fabrication method has been developed to produce very clean, well-defined and highly reproducible sub-wavelength fiber probes with metallic apertures of a desired diameter for use in near-field scanning optical microscopy (NSOM). The ion beam milling process can eliminate the obstruction of apertures caused by conventional metallic coating techniques, and thus increase the optical output.

See U.S. Patent No. 6,633,711

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Additional Information

INSTITUTION

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PATENT STATUS

U.S. Patent 6,664,126

LICENSE STATUS

Available for exclusive license

CATEGORIES

- Imaging devices

EXTERNAL RESOURCES

- [US Patent 6,633,711](#)

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